



1765

# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Karola Richter et al.  
Serial No: 10 / 553 728 Art Unit: 1765  
Filing Date: October 14, 2005  
Title: SILICON SUBSTRATE COMPRISING POSITIVE ETCHING PROFILES  
WITH A DEFINED SLOPE ANGLE, AND PRODUCTION METHOD.

October 17, 2007

Attorney's Docket No.: HMP201T3

## TRANSMITTAL LETTER

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313

SIR:

Transmitted herewith for filing is:

<X> SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT dated October 17, 2007

<X> INFORMATION DISCLOSURE CITATION

(X) The applicant hereby petitions the Commissioner of Patents and Trademarks to extend the time for response to any Office Action outstanding in the above captioned matter as necessary to avoid abandonment of the application. Please charge my deposit account No.11-0224 in the amount required to cover the cost of the extension. Any deficiency or overpayment should be charged or credited to the above account.

(X) The Commissioner is hereby authorized to charge any fees under 37 CFR 1.16, and 1.17, after a mailing of a Notice of Allowance under 37 CFR 1.18 or any additional fees which may be required during the entire pendency of the application, or credit any overpayment, to Acct. No.11-0224. A duplicate copy of this sheet is enclosed. If and only if account funds should be insufficient, immediately contact our associate, Lisa Zumwalt, at (703)415-0579, who will pay immediately to avoid deprivation of rights.

( ) Please charge my Deposit Account No.11-0224 in the amount of \$\_\_\_\_\_. A duplicate copy of this sheet is enclosed.

A signature or signatures required for the above recited document(s) is (are) provided herebelow. Such signature(s) also provide(s) ratification for any required signature appearing to be defective in the above recited document(s).

*Horst M. Kasper*

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## CERTIFICATE OF MAILING:

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313

on **OCT 18 2007**

Signature: *[Signature]*

Date: **OCT 18 2007**

/am

IN THE UNITED STATES PATENT AND TRADEMAR OFFICE

Applicant: Karola Richter et al.  
Serial No: 10/553,728  
Filing Date: January 3, 2006  
Title: SILICON SUBSTRATE COMPRISING POSITIVE ETCHING PROFILES  
WITH A DEFINED SLOPE, ANGLE, AND PRODUCTION  
METHOD  
Examiner: Patricia Ann George Art Unit: 1765



October 17, 2007

HMP201S3

**SUPPLEMENTAL INFORMATION DISCLOSURE  
STATEMENT UNDER 37 CFR § 1.97.**

**Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450**

SIR:

Additional reference has come to the attention of the applicant in the instant case.

The attorney understands that the applicants believe that these references are not closer to the present invention than the state of the art which is otherwise present in the file of this case.

The following is a listing of the references in question:

-US Patent Application Ser. No. 11/261,241, filed October 27, 2005.

Applicants are respectfully submitting a form PTO-1449 with all references listed therein and including citation in the application.

Consideration of the reference document during the examination of the present application is respectfully requested.

Respectfully submitted,

Karola Richter et al.

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